

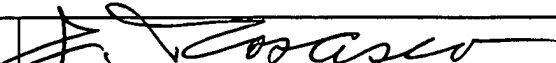


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| Substitute for Form 1449 A & B/PTO <u>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</u> <i>(use as many sheets as necessary)</i> | | | | <i>Complete if Known</i> | |
| | | | | Application Number | 10/519,991 |
| | | | | Confirmation Number | 9188 |
| | | | | Filing Date | January 4, 2005 |
| | | | | First Named Inventor | Shinichi ISHIBASHI |
| | | | | Art Unit | 1795 |
| | | | | Examiner Name | Stephen D. Rosasco |
| Sheet | 1 | of | 1 | Attorney Docket Number | Q85552 |

| U.S. PATENT DOCUMENTS | | | | | |
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| Examiner Initials* | Cite No. ¹ | Document Number | | Publication Date MM-DD-YYYY | Name of Patentee or Applicant of Cited Document |
| | | Number | Kind Code ² (if known) | | |
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| Examiner Initials* | Cite No. ¹ | Foreign Patent Document | | | Publication Date MM-DD-YYYY | Name of Patentee or Applicant of Cited Document | Translation ⁶ |
| | | Country Code ³ | Number ⁴ | Kind Code ⁵ (if known) | | | |
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| NON PATENT LITERATURE DOCUMENTS | | | |
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| Examiner Initials* | Cite No. ¹ | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city, and/or country where published. | Translation ⁶ |
|  | | Ted LIANG, et al. "ENHANCED OPTICAL INSPECTABILITY OF PATTERNED EUVL MASK", Intel Corporation Components Research, Proceedings of SPIE Vol. 4562 (2002), pgs. 288-296. | |
|  | | Semiconductor Equipment and Materials International SEMI Draft Document 3414 "SPECIFICATION FOR ABSORBING FILM STACKS AND MULTILAYERS ON EXTREME ULTRAVIOLET LITHOGRAPHY MASK BLANKS" Document Number 3414 dated 04/29/2002. | |
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| Examiner Signature |  | Date Considered | 1/08 |
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